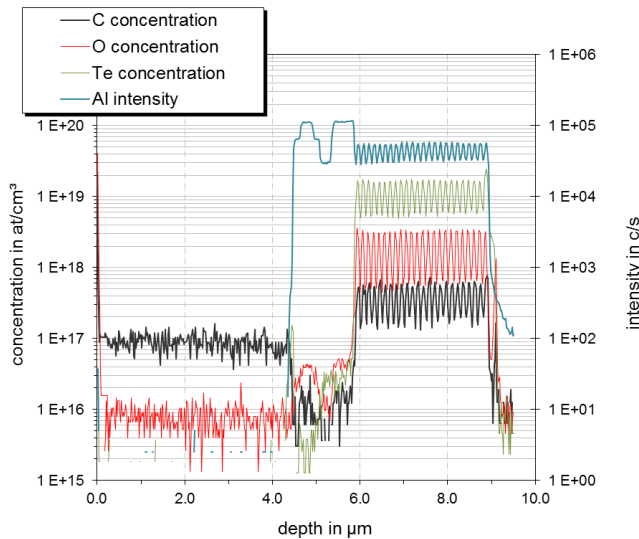
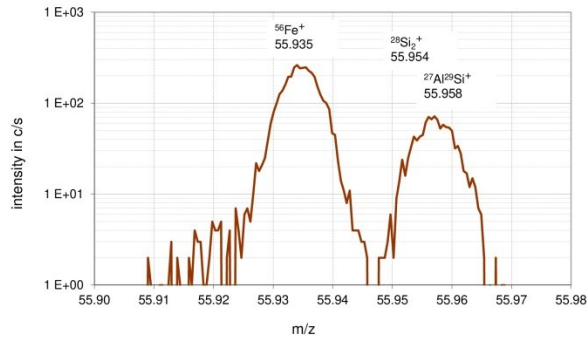


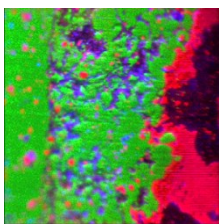
# SIMS Analytics of Dopants, Impurities and Matrix Compositions



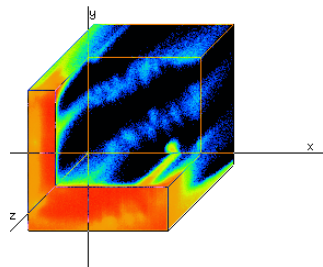
Quantification of dopants and impurities in layer systems:  
 Depth profile of the C, O, and Te concentrations on the InGaAlP-AlGaAs layer system of a LED.



High resolved mass spectrum



Lateral element distribution  
 of a biological Titanium implant  
 (Ti - green, Na - blue, Ca - red)



Three dimensional  
 distribution of oxygen in  
 silicon

## Main Applications

- Quantification of dopants and impurities
  - Access to a huge pool of calibration standards
- Quantification of matrix compositions
- Depth profiling
- Mapping
- Space-resolved element quantification
- Three dimensional analyses of microvolumes
- Mass spectra
- Failure analyses

## Materials (Selection)

- III/V Semiconductors (GaAs, GaN, GaP, InP, ternary, quaternary)
- Silicon, germanium, silicides
- II/VI semiconductors (CdTe, ZnO, ZnSe)
- Optical multilayers
- Metal layer structures, contact systems
- Solar cells (Si, CIGS, CIGSe)
- Metal ceramic and ceramic compound systems
- Polymers
- Medical and biological samples (implants, dental materials)

## Strengths of SIMS

- High sensitivities
- Very low detection limits (ppm and below)
- Depth profiles with high depth resolution (1 nm) and low detection limits
- Detection of any chemical element, from H to U
- High lateral resolution (1µm)
- High dynamic range (6 orders of magnitude)

## Limitations of SIMS

- Destruction of the sample surface
- Mixing and recoil processes
- Topographical effects, surface roughness
- High variation of ionisation cross sections
- Matrix dependence of detection sensitivities
- No information about chemical bonds
- Solid and vacuum resistant samples are required